	Application No. Applicant(s)		,	
Notice of Allowability	10/634,756	JUN ET AL.	JUN ET AL.	
	Examiner	Art Unit		
	Nikita Wells	2881	pw	
Th MAILING DATE of this communication app All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85 NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT R of the Office or upon petition by the applicant. See 37 CFR 1.31	6 (OR REMAINS) CLOSED 6) or other appropriate comm 8IGHTS. This application is	in this application. If not inclu	ided	
1. This communication is responsive to <u>06 August 2003.</u>		•		
2. 🖾 The allowed claim(s) is/are <u>1-40</u> .		*		
3. \boxtimes The drawings filed on <u>06 August 2003</u> are accepted by the	e Examiner.			
4. Acknowledgment is made of a claim for foreign priority u a) All b) Some* c) None of the: 1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). * Certified copies not received: Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONN THIS THREE-MONTH PERIOD IS NOT EXTENDABLE. 5. A SUBSTITUTE OATH OR DECLARATION must be submin INFORMAL PATENT APPLICATION (PTO-152) which giv 6. CORRECTED DRAWINGS (as "replacement sheets") must be comply including changes required by the Notice of Draftspers 1) hereto or 2) to Paper No./Mail Date	e been received. e been received in Applicate been received in Applicate becoments have been received of this communication to find ENT of this application. Initted. Note the attached Expess reason(s) why the oathers to be submitted. Son's Patent Drawing Reviews	ion No ed in this national stage applic le a reply complying with the re CAMINER'S AMENDMENT or or declaration is deficient.	equirements	
Paper No./Mail Date Identifying indicia such as the application number (see 37 CFR 1	.84(c)) should be written on	the drawings in the front (not th	ne back) of	
each sheet. Replacement sheet(s) should be labeled as such in to the sheet. The property of the sheet sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) should be labeled as such in the sheet (s) she	he header according to 37 C sit of BIOLOGICAL MAT	FR 1.121(d). ERIAL must be submitted		
Attachm nt(s) I. ☑ Notice of References Cited (PTO-892)	T D Niego ver			
2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948)		nformal Patent Application (PT Summary (PTO-413),	O-152)	
 Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date 051304 	Paper No	/Mail Date s Amendment/Comment		
Examiner's Comment Regarding Requirement for Deposit	8. 🛭 Examiner's	Statement of Reasons for All	owance	
of Biological Material	9. 🗌 Other	ed ev ve e e e e e e e e e e e e e e e e	a managaran a lamana	
*		Nikita Wells Primary Examiner Art Unit: 2881		

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Detailed Action

Allowable Subject Matter

- 1. Claims 1-40 are allowed.
- 2. The following is an examiner's statement of reasons for allowance:

With respect to the independent claims 1, 11, and 18, prior art fails to disclose or make obvious, in addition to the accompanying features of the claims, a method for monitoring an ion implanter, comprising: positioning a substrate behind an interceptor for intercepting a portion of an ion beam to be irradiated toward the substrate; irradiating a first ion beam toward the substrate to form a first shadow on the substrate, rotating the substrate about a central axis of the substrate, irradiating a second ion beam toward the substrate to form a second shadow on the substrate, and measuring a dosage of ions implanted into the substrate to monitor whether the rotation of the substrate has been normally performed.

With respect to the independent claim 24, prior art fails to disclose or make obvious, comprising in addition to the accompanying features of the claims, an ion implanter with a chuck disposed in the ion implantation chamber for supporting the substrate, which is tilted at a predetermined angle with respect to an advancing direction of the ion beam; a first driving unit for rotating the substrate about a central axis of the substrate in order to change an incidence angle of ion beam; and a shadow jig for intercepting a portion of the ion beam in order to form a shadow on the substrate during the ion implantation process, wherein the shadow is formed to monitor whether the substrate has been normally rotated during the ion implantation process.

The dependent claims 2-10, 12-17 and 23, 19-22, and 25-40, are allowable by virtue of their dependence upon the independent claims 1, 11, 18, and 24, respectively.

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Conclusion

- 3. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. R.J.C. Mitchell (6,566,661 B1) and Ryding et al. (6,555,832 B1) disclose an ion implanter with a beam and wafer angle alignment arrangement wherein the substrate tilt and rotation are considered. Larsen et al. (6,690,022 B2) disclose an ion implanter with a device for measuring the incident angle of the ion beam impinging onto a planar substrate.
- 4. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."
- 5. Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).
- 6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Nikita Wells whose telephone number is (571) 272-2484. The examiner can normally be reached on 8:30 AM 5:00 PM. If attempts to reach the examiner by

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telephone are unsuccessful, the examiner's supervisor, John R. Lee can be reached on (571) 272-2477. The central fax phone number for the organization where this application or proceeding is assigned is (703) 872-9306.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 308-0956.

Nikita Wells, Primary Examiner

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May 13, 2004